



P A T E N T

Attorney Docket No.  
033082 M 275

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of:	)	<b>CONFIRMATION NO.: 6774</b>
	)	
Kazuhide HASEBE, et al.	)	
	)	
U.S. Serial No.: 10/552,262	)	Group Art Unit: 1765
	)	
Filed: October 5, 2005	)	Examiner: Lan Vinh
For: SILICON DIOXIDE FILM REMOVING METHOD AND PROCESSING SYSTEM		

**RESPONSE TO OFFICE ACTION DATED SEPTEMBER 26, 2007**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in reply to the Office Action mailed September 26, 2007, to which the time for response was set to expire December 26, 2007. A Petition for Extension of Time for one month and the requisite fee are submitted herewith to extend the date for reply up to and including January 26, 2008. Therefore, please accept this Response as timely filed.

Kindly amend the above-identified patent application as set forth in the listing of claims below.